

INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Not for submission under 37 CFR 1.99)	Application Number		10588981	
	Filing Date		2006-08-10	
	First Named Inventor		RODERICK BOSWELL	
	Art Unit		2881	
	Examiner Name		NOT YET ASSIGNED	
	Attorney Docket Number		F146	

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/M.S./	1	LEUNG, KA-NGO, "Plasma sources for electrons and ion beams," J. Vac. Sci. Technology B, Nov/Dec 1999, Vol. 17, No. 6., pages 2776-2778. Nov. 1999	<input type="checkbox"/>
/M.S./	2	MATHEW, JOSE V., ET AL., "Subcutoff microwave driven plasma ion sources for multielemental focused ion beam systems," Review of Scientific Instruments, 2008, Vol 79, 5 pages. June, 2008	<input type="checkbox"/>
/M.S./	3	ONO, L.K., ET AL., "A Compact Gas Cluster Ion Beam Source of QSEC," 2003, 4 pages.	<input type="checkbox"/>
/M.S./	4	Singleton Accelerator Systems: Coaxial and In-Line Positive Ion Accelerators. 6 pages.	<input type="checkbox"/>

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Examiner Signature	/Meenakshi Sahu/	Date Considered	08/27/2010
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